

Semiconductor devices - Mechanical and climatic test  
methods - Part 6: Storage at high temperature

## EESTI STANDARDI EESSÕNA

## NATIONAL FOREWORD

See Eesti standard EVS-EN 60749-6:2017 sisaldab Euroopa standardi EN 60749-6:2017 ingliskeelset teksti.	This Estonian standard EVS-EN 60749-6:2017 consists of the English text of the European standard EN 60749-6:2017.
Standard on jõustunud sellekohase teate avaldamisega EVS Teatajas	This standard has been endorsed with a notification published in the official bulletin of the Estonian Centre for Standardisation.
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Standard on kättesaadav Eesti Standardikeskusest.	The standard is available from the Estonian Centre for Standardisation.

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English Version

**Semiconductor devices - Mechanical and climatic test methods -  
Part 6: Storage at high temperature  
(IEC 60749-6:2017)**

Dispositifs à semiconducteurs - Méthodes d'essais  
mécaniques et climatiques - Partie 6: Stockage à haute  
température  
(IEC 60749-6:2017)

Halbleiterbauelemente - Mechanische und klimatische  
Prüfverfahren - Teil 6: Lagerung bei hoher Temperatur  
(IEC 60749-6:2017)

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European Committee for Electrotechnical Standardization  
Comité Européen de Normalisation Electrotechnique  
Europäisches Komitee für Elektrotechnische Normung

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## European foreword

The text of document 47/2347/FDIS, future edition 2 of IEC 60749-6, prepared by IEC/TC 47 "Semiconductor devices" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN 60749-6:2017.

The following dates are fixed:

- latest date by which the document has to be implemented at national level by publication of an identical national standard or by endorsement (dop) 2018-01-07
- latest date by which the national standards conflicting with the document have to be withdrawn (dow) 2020-04-07

This document supersedes EN 60749-6:2002.

Attention is drawn to the possibility that some of the elements of this document may be the subject of patent rights. CENELEC shall not be held responsible for identifying any or all such patent rights.

## Endorsement notice

The text of the International Standard IEC 60749-6:2017 was approved by CENELEC as a European Standard without any modification.

In the official version, for Bibliography, the following notes have to be added for the standards indicated:

IEC 60749-20	NOTE	Harmonized as EN 60749-20.
IEC 60749-43	NOTE	Harmonized as EN 60749-43 <sup>1)</sup> .

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1) At draft stage.

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## SEMICONDUCTOR DEVICES – MECHANICAL AND CLIMATIC TEST METHODS –

### Part 6: Storage at high temperature

#### 1 Scope

The purpose of this part of IEC 60749 is to test and determine the effect on all solid state electronic devices of storage at elevated temperature without electrical stress applied. This test is typically used to determine the effects of time and temperature, under storage conditions, for thermally activated failure methods and time-to-failure of solid state electronic devices, including non-volatile memory devices (data-retention failure mechanisms). This test is considered non-destructive but should preferably be used for device qualification. If such devices are used for delivery, the effects of this highly accelerated stress test will need to be evaluated.

Thermally activated failure mechanisms are modelled using the Arrhenius equation for acceleration, and guidance on the selection of test temperatures and durations can be found in IEC 60749-43.

#### 2 Normative references

There are no normative references in this document.

#### 3 Terms and definitions

No terms and definitions are listed in this document.

ISO and IEC maintain terminological databases for use in standardization at the following addresses:

- IEC Electropedia: available at <http://www.electropedia.org/>
- ISO Online browsing platform: available at <http://www.iso.org/obp>

#### 4 Test apparatus

The controlled temperature chamber required for this test shall be capable of maintaining the test temperature within the tolerances specified in Table 1. Electrical equipment shall be capable of performing the appropriate measurements for the devices being tested, including writing and verifying the required data retention pattern(s) for nonvolatile memories.

#### 5 Procedure

##### 5.1 Test conditions

The devices under test (DUT) shall be subject to continuous storage (except when there is a requirement in the applicable procurement document to return the DUTs to room ambient for interim electrical measurements) at one of the temperatures specified in Table 1. Qualification and reliability monitoring test conditions typically require a test duration of 1 000 °C<sub>0</sub><sup>+24</sup> at test temperature B of Table 1. Other test conditions can be used as appropriate.